

**Remarks**

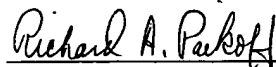
Reconsideration and reversal of the rejections expressed in the Office Action of December 28, 2005 are respectfully contended in view of the following remarks and the application as amended. The present invention relates to a method and system for preventing wafer breakage during wet processing. A wet processing tank is provided wherein a wafer is to be placed within the wet processing tank. A sensor is provided within the wet processing tank wherein the sensor continuously counts bubbles formed within the wet processing tank in a time interval. The sensor is queried wherein if a bubble count within the time interval exceeds a trigger point, then an alarm is given so that a process lot will not be entered into the wet processing tank.

Claims 1-9 and 19-25 were rejected under 35 U.S.C. §102(e) as being anticipated by Nam (US 2004/0035449 A1). In order to enhance the prosecution of the present application, enclosed with this Amendment and Response is a Declaration under 37 CFR 1.131, which establishes that the present invention was reduced to practice prior to the July 17, 2003 filing date of Nam '449. Thus, this rejection is overcome.

For all of the above reasons, it is respectfully contended that the solicited claims define patentable subject matter. Reconsideration and reversal of the rejections expressed in the Office Action of December 28, 2005 are respectfully submitted. The Examiner is invited to call the undersigned if any questions arise during the course of reconsideration of this matter.

Respectfully submitted,

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